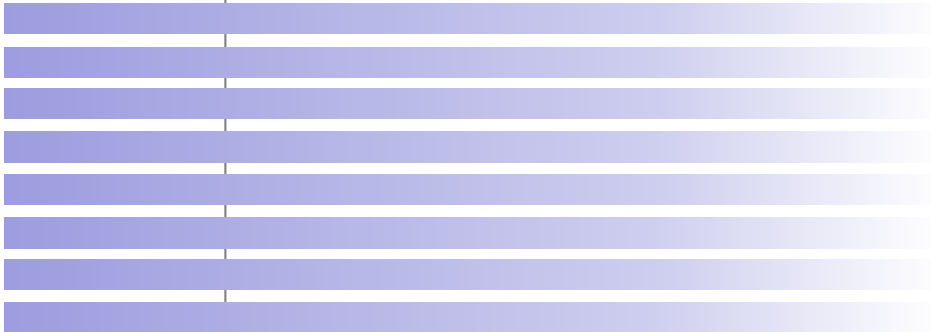




SILICON WAFER ANALYZER

WA 2560M



Silicon Wafer
Analyzer
WA 2560M



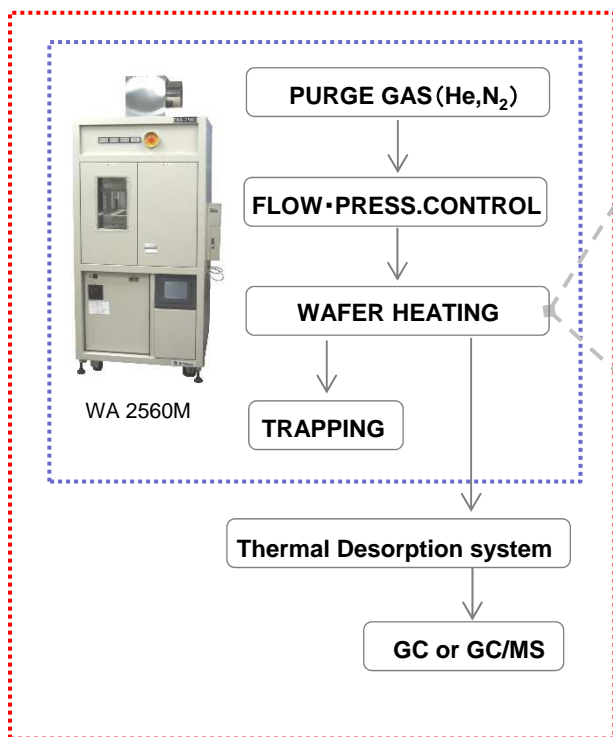
Silicon wafer analyzer WA2560M is for trapping samples adhered on silicon wafer surfaces under the semiconductor process.

WA2560M is an OFF LINE System that traps samples of thermal desorbed organic compounds with a sample tube.

FEATURES

- 3~12" (76~300 mm) SILICON WAFER ARE MEASURABLE
- SILICON WAFER SURFACE (ONE SIDE) IS MEASURABLE AT 700 °C
- HIGH SENSITIVITY ANALYSIS IS AVAILABLE W/QUARTZ CHAMBER & INERTNESS SAMPLE LINE. (<pg/cm)
- New** ● Less purge gas consumption at waiting mode.
- New** ● PURGE GAS (He, N₂) SWITCHING FUNCTION
- New** ● EASY OPERATION : SYSTEM CONTROL IS AVAILABLE ON THE TOUCH PANEL

SYSTEM FLOW



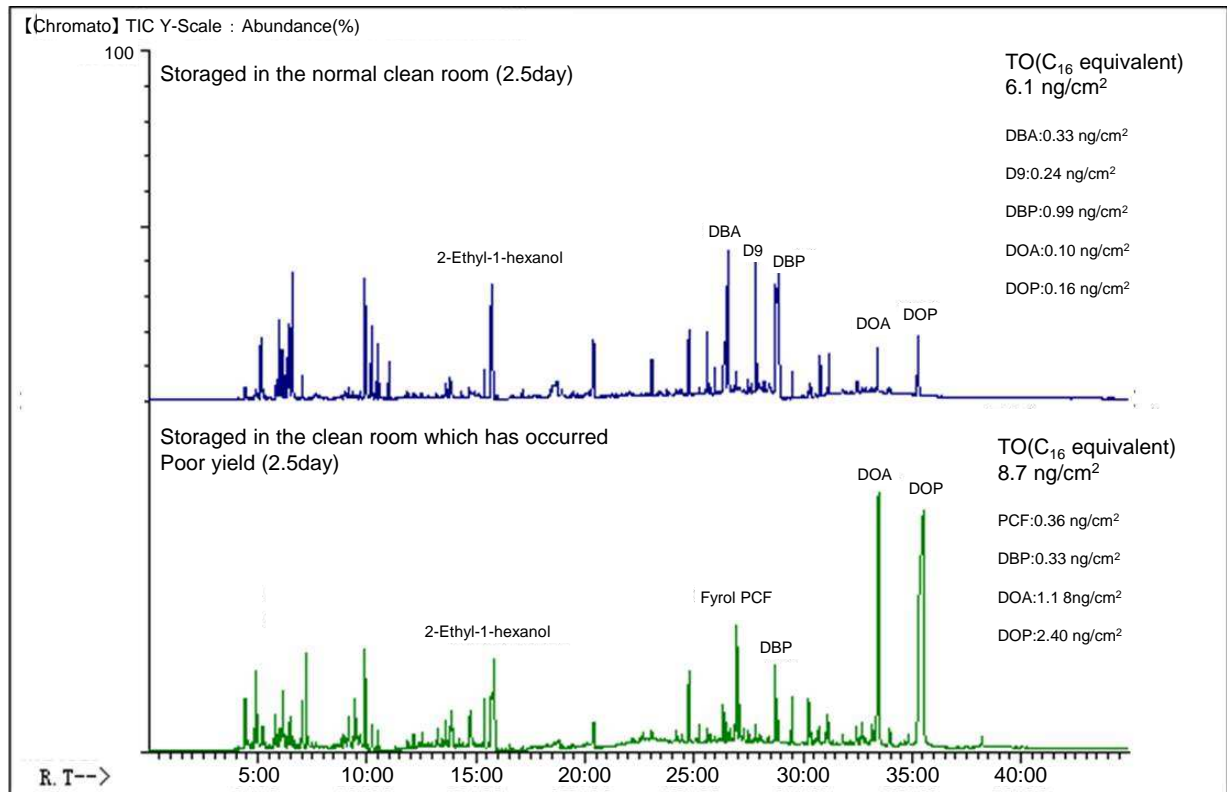
QUARTZ CHAMBER

Purge gas is flown thru circumference holes on the chamber base. Only desorbed gas from the wafer surface is trapped with a trapping tube using a suction pump. 12inch (300 mm) can be measured.

HEATER FURNACE

A wafer is heated to desorb trace organic compounds adhered on silicon wafer surface. It can be heated at 700 °C as max.temp. After heating, inside air is sent to the outside from the heater furnace bottom or the system back for cooling the furnace.

Wafer analysis



Specifications

QUARTZ CELL	MATERIAL WAFER SIZE TRAPPING SYSTEM	: QUARTZ : 3~12" (76~300 mm) : ONE SIDE TRAPPING (BACK SIDE EXHAUST)
HEATER FURNACE	TYPE OPEN/CLOSE OPERATION TEMP.	: SQUARE TOP COVER OPEN/CLOSE HEATER FURNACE : AIR CYLINDER ACTUATOR FOR OPENING/CLOSING THE TOP COVER : 100~700 °C
FLOW·PRESSURE CONTROL UNIT	CARRIFER GAS PURGE GAS TRAPPING FLOW BACK SIZE EXHAUST	: FIX PRES. CONTROL(30~300 kPa) AT He : FIX FLOW CONTROL(Max.500 mL/min) AT He : FIX FLOW CONTROL(Max.200 mL/min) AT He : FIX FLOW CONTROL(Max.200 mL/min) AT He

WA 2560M SPEC.

TRAP UNIT	TRAPPING TUBE TRAPPING TEMP.	: 1/4"OD OR 6 mm TRAPPING TUBES : ROOM TEMP. (COOLING TO A ROOM TEMP. BY COOLING FAN)
HEATER BLOCK UNIT	TEMP.SETTING	: 270 °C~300 °C
WA 2560M	DIMENSIONS WEIGHT POWER SUPPLY	: 1000(W) × 1100(D) × 2130(H) mm (INCLUDING THE TOP DUCT) 450 kg APPROX. : AC200 V, 50/60 Hz, 40 A